

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Sakae KOYATA et al. Group Art Unit : 1792  
Appl. No. : 10/561,821 Examiner : OLSEN, Allan W.  
Filed : February 7, 2007 Confirmation No. : 2851  
For : PROCESSING METHOD OF SILICON WAFER

**AMENDMENT UNDER 37 C.F.R. § 1.116**

Commissioner for Patents  
U.S. Patent and Trademark Office  
Customer Service Window, Mail Stop **AMENDMENT**  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

This Amendment is responsive to the Official Action of the U.S. Patent and Trademark Office dated January 7, 2010. Reconsideration and withdrawal of the rejections of record are respectfully requested in view of the following amendments and remarks. Inasmuch as this response is filed by March 8, 2010, no extension of time is required. Further, Applicants note that this response is filed within two months of a Final Office Action, and respectfully request prompt notification of the status of this application. If the Office deems any extension of time to be required, Applicants request such extension and expressly authorize the charging of such fee to Deposit Account 19-0089.

Please amend the application as follows:

**Amendments to the Specification** begin on page 2 of this paper;

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 3 of this paper; and

**Remarks** begin on page 4.